

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hidekazu MIYAIRI et al.

Serial No. 10/663,671

Filed: September 17, 2003

For: LASER APPARATUS, LASER IRRADIATION
METHOD, AND MANUFACTURING METHOD
OF SEMICONDUCTOR DEVICE



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Group Art Unit: 1722

Examiner: Felisa Carla Hiteshew

Date: January 11, 2006

RESPONSE TO REQUEST FOR RESTRICTION REQUIREMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Request for Restriction Response mailed December 12, 2005,
Applicants responds as follows: